



Photoluminescent colour centres in lithium fluoride film detectors for gamma rays

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Abstract

Passive solid-state detectors based on lithium fluoride (LiF) thin films, nominal thickness 1, 1.5 and 2 µm, were grown by thermal evaporation on glass, Suprasil® and Si(100) substrates at ENEA C.R. Frascati. These radiation imaging detectors are characterized by high intrinsic spatial resolution over a large field of view, wide dynamic range and simplicity of use. Their principle of operation is the optical reading of the visible photoluminescence (PL), emitted by radiation-induced F₂ and F₃⁺ colour centres (CCs) stable at room temperature, by using fluorescence microscopy technique. The LiF filmbased detectors grown on Si(100) were irradiated at several doses in the range from 20 to 10³ Gy with gamma rays at the Calliope irradiation facility (ENEA C.R. Casaccia). Their PL response shows a linear behaviour as a function of the irradiation dose for all three film thicknesses. The lowest detected dose, delivered to the thickest LiF film, is estimated at 20 Gy.

Thermally-evaporated LiF radiation imaging detectors

Colour Centres in LiF



grown by thermal evaporation are strongly dependent on the nature of the substrate and the deposition parameters main such as substrate temperature, total thickness, deposition rate.

Main deposition parameters

- \checkmark pressure < 1 mPa;
- \checkmark deposition rate: 0.5 ÷ 2 nm/s;
- \checkmark film thickness: up to few μ m
- ✓ substrate temperature: 30 ÷ 350 °C
- ✓ substrate material: glass, silica, Si, plastic and metal layers, etc.



- Radiation-induced F_2 and F_3^+CCs (a) consisting in two electron bound to two and three close anion vacancies, respectively.
- Irradiation of LiF gives rise to temperature stable formation of F_2 and F_3^+ CCs, with almost overlapping absorption bands peaked at 444 and 448 nm, respectively (b).
- Under optical pumping in their optical absorption bands, F_2 and F_3^+ CCs emit broad PL bands peaked at 678 and 541 nm respectively (b), which can be read in non-destructive way using fast and efficient optical reading techniques such as fluorescence conventional and confocal microscopy.



Atomic Force Microscopy Characterization

 \succ The polycrystalline LiF films grown on Si(100) and glass substrates were characterized with Atomic Force Microscopy (AFM) investigating their surface morphology.

LiF film detectors PL response

 \succ The LiF films grown on Si(100) were irradiated with gamma rays at several doses



3D AFM images of LiF films grown on Si(100) substrate

> Root Mean Square roughness (RMS) and Average Grain Size (AGS) were investigated for LiF film-based detectors grown on glass and Si(100) substrate.



- in the range from 20 to 10^3 Gy.
- > LiF film detectors PL response, investigated by using a fluorescence microscope, shows a linear behaviour as a function of the irradiation dose for all three film thicknesses.
- > The lowest detected dose, delivered to the thickest LiF film, was estimated at 20 Gy.



<u>CONCLUSIONS</u>

Preliminary AFM characterization shows that RMS and AGS respectively increases and decreases with LiF film thickness.



function of the irradiation dose in the investigated dose range from 20 to 10³ Gy for three film thicknesses;

